

AMENDMENTS TO THE SPECIFICATION

Please substitute the first paragraph of SUMMARY OF THE INVENTION with the following paragraphs now appearing in the currently filed specification:

"The present invention intends to provide an improved lens system for a plurality of charged particles. Thereby, one object is to improve the symmetry of the lens field used for imaging the charged particle beam. Another object is to provide an advantageous manufacturing method for the lens systems. ~~Further, a lens system according to independent claims 1 and 21, a manufacturing method according to independent claim 17 and a multiple charged particle beam device according to independent claim 34 are provided.~~

In one embodiment, the present invention provides a lens system for a plurality of charged particle beams, the lens system comprising a lens system for a plurality of charged particle beams, comprising at least two lens modules, each comprising a first pole piece, a second pole piece and at least one opening for a charged particle beam, and at least one excitation coil providing a magnetic flux to the at least two lens modules, wherein each lens module constitutes a component.

In one embodiment, the present invention also provides a lens system for a plurality of charged particle beams comprising an excitation coil providing a magnetic flux to a pole piece unit having a first pole piece, a second pole piece and at least two openings for charged particle beams, wherein the openings are arranged in one row, thereby forming a lens row and wherein the pole piece unit has an elongated shape.

In one another embodiment, the present invention provides a method for manufacturing a lens system comprising manufacturing a plurality of lens modules, each comprising a first pole piece, a second pole piece and at least one opening for a charged particle beam, and providing a common excitation coil for at least two lens modules.

In one embodiment, the present invention provides a multiple charged particle beam device comprising a charged particle beam source, a detector for detecting

secondary particles, beam shaping means, a housing for the charged particle beam column, wherein the housing can be evacuated, at least one lens system comprising at least two lens modules, each comprising a first pole piece, a second pole piece and at least one opening for a charged particle beam, and at least one excitation coil providing a magnetic flux to the at least two lens modules, wherein each lens module constitutes a component."